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R. Jones  
10/8/02

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. .... 09/512,968  
Filing Date ..... February 24, 2000  
Inventor ..... David R. Hembree  
Assignee ..... Micron Technology, Inc.  
Group Art Unit ..... 2858  
Examiner ..... V. Nguyen  
Attorney's Docket No. .... MI22-1363  
Title: Electronic Device Workpiece Processing Apparatus and Method of Communicating Signals Within an Electronic Device Workpiece Processing Apparatus

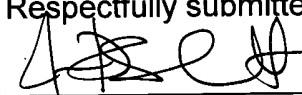
### SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

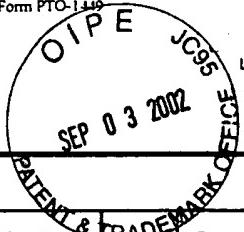
The attached form PTO-1449 is submitted in compliance with 37 CFR §1.56. No admission is made regarding whether all the submitted references are prior art.

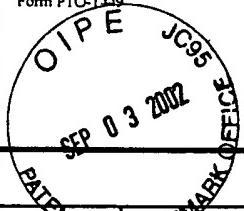
Dated: 9/3/03

Attorney:

Respectfully submitted,  
  
James D. Shaurette  
Reg. No. 39,833

EV 182664188

Form PTO-144  LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-1363	SERIAL NO. 09/512,968
				APPLICANT David R. Hembree			
				FILING DATE February 24, 2000		GROUP 2832	
				U.S. PATENT DOCUMENTS			
*Examiner Initials	TRADEMARK OFFICE	Document Number	Date	Name	Class	Subclas s	Filing Date If Appropriate
		AA 3,440,407	4/22/69	Golstos et al.			
		AB 3,614,345	10/19/71	Quinn			
		AC 3,683,306	8/8/72	Bulthius et al.			
		AD 4,332,081	6/1/82	Francis			
		AE 4,518,944	5/21/85	Faris			
		AF 4,703,555	11/3/87	Hubner			
		AG 5,141,334	8/25/92	Castles			
		AH 5,347,869	9/20/94	Shie et al.			
		AI 5,406,109	4/11/95	Whitney			
		AJ 5,436,646	7/25/95	McArthur et al.			
		AK 5,446,437	8/29/95	Bantien et al.			
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclas s	Translation
							Yes      No
		AL 2336778	7/1977	France			
		AM 56-12521	2/1981	Kobayashi, Japan			
		AN 2-268462	11/1990	Yamanishi, Japan			
		AO					
		AP					
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AR		"Application Guide Temperature Sensors", Watlow Electrical Manufacturing Company Catalog, pp. 775-778, 1992/1993.				
	AS		"In-Situ survey System of Resistive and Thermoelectric Properties of Either Pure or Mixed Materials in Thin Films Evaporated Under Ultra High Vacuum", Lechevallier, LeHuerou, Richon, Sarrazin, & Gouault, J. Phys. III France, Vol. 5, pp. 409-418, 04/95 (Abstract only).				
	AT		"Temperature Metrology for CD Control in DUV Lithography", Jeffrey Parker and Wayne Renken, pp. 111-112, 114, 116, 09/17/97.				
EXAMINER				DATE CONSIDERED			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

Form PTO-1449  <b>U.S. DEPARTMENT OF COMMERCE</b> <b>PATENT AND TRADEMARK OFFICE</b> <b>LIST OF ART CITED BY APPLICANT</b> (Use several sheets if necessary)				ATTY. DOCKET NO. M122-1363		SERIAL NO. 09/512,968	
				APPLICANT David Hembree			
				FILING DATE February 24, 2000		GROUP 2858	
<b>U.S. PATENT DOCUMENTS</b>							
*Examiner's Initial	TRADEMARK	Document Number	Date	Name	Class	Subclas s	Filing Date If Appropriate
	AA	5,612,574	3/18/97	Summerfelt et al.			
	AB	5,719,333	2/17/98	Hosoi et al.			
	AC	5,831,333	11/3/98	Malladi et al.			
	AD	5,919,548	7/6/99	Barron et al.			
	AE	5,551,283	9/3/96	Manaka et al.			
	AF	5,492,011	2/20/96	Amano et al.			
	AG						
	AH						
	AJ						
<b>FOREIGN PATENT DOCUMENTS</b>							
		Document Number	Date	Country	Class	Subclas s	Translation
	AK						Yes
	AL						No
	AM						
	AO						
<b>OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)</b>							
	AP		"NTC and PTC Thermistors"; <a href="http://www.thermodisc.com/ntcptc.html">http://www.thermodisc.com/ntcptc.html</a> ; 1/7/98; 2 pages.				
	AR		"DI-5B35 Linearized 4-Wire RTD Input"; <a href="http://www.dataq.com/di5b35.html">http://www.dataq.com/di5b35.html</a> ; 1/7/98; 2 pages.				
	AS		"RTD"; <a href="http://www.mtisensors.com/rtds.html">http://www.mtisensors.com/rtds.html</a> ; 1/7/98; 3 pages.				
	AT		"Low Cost Thermal-Ribbon (TM) uses thin film RTD"; <a href="http://www.minco.com/s17624nr.html">http://www.minco.com/s17624nr.html</a> ; 1/7/98; 1 page.				
	AU		"Silicon Processing for the VLSI Era"; Volume 1 - Process Technology, Second Edition; S. Wolf et al.; 2000; pps 22-25 and pps. 841-845.				
EXAMINER				DATE CONSIDERED			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							